

ELECTROMAGNETIC FIELD CALCULATIONS FOR
MICROLENS OPTICAL SYSTEMS

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ELECTROMAGNETIC FIELD CALCULATIONS FOR MICROLENS OPTICAL SYSTEMS

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Micro lenses are becoming more widely used in modern optical equipment. When the microlens diameter is comparable with the incident electromagnetic illumination wavelength, diffraction effects through the microlens aperture dominate and significantly affect the microlens optical properties leading to differences from that predicted by ordinary geometrical optics theory. In this work, the continuous-profile symmetrical biconvex microlens is selected for investigation. Its optical properties, with both monochromatic plane wave and TEM00 mode Gaussian beam illumination, are studied using the full-field Separation-of-Variables method (SVM) in the oblate spheroidal coordinate system by calculating the electromagnetic field distributions inside of and adjacent to the microlens. The microlens optical properties are also compared with the corresponding geometrical optics theory.

The investigations and discussions include the focusing properties of a single microlens with monochromatic plane wave illumination, the beam transformation properties of a single microlens with monochromatic TEM00 mode Gaussian beam illumination, the axial combination properties of dual microlenses with monochromatic plane wave and TEM00 mode Gaussian beam illumination, the interference properties

between dual parallel-arranged microlenses with monochromatic plane wave illumination, and the imaging properties of a single microlens with monochromatic plane wave and TEM₀₀ mode Gaussian beam illumination. The optical properties of microlens optical systems are found to be similar to that given by the geometrical optics theory. The microlens actual focal length is measured for different profile and diameter microlenses and is compared with its corresponding geometrical focal length. It is shown that the microlens actual focal length is an important parameter and can be used to describe and approximately formulate the microlens optical properties. The transmitted beam waist position through a microlens calculated using the Rayleigh Range method (RRM) with the microlens actual focal length closely matches the exact value determined using the Separation-of-Variables method in the oblate spheroidal coordinate system. The axial combination properties of dual microlenses with monochromatic plane wave illumination and the imaging properties of a single microlens can also be described using the geometrical imaging formula with the microlens actual focal length.

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Table of Contents

| | |
|---|-----------|
| 1. Introduction | 1 |
| 1.1 Computational electromagnetics method | 3 |
| 1.2 Review of micro optics research | 6 |
| 2. Introduction to the Separation-of-Variables Method in the Oblate Spheroidal | |
| Coordinate System | 14 |
| 2.1 Spheroidal coordinate system | 14 |
| 2.2 Oblate spheroid coordinate system and microlens geometry | 14 |
| 2.3 Separation-of-Variables method in the oblate spheroidal coordinate system | 19 |
| 2.4 Monochromatic electromagnetic illumination sources | 26 |
| 3. Focusing and Beam Transformation Properties of A Single Microlens | 29 |
| 3.1 Normal monochromatic plane wave illumination | 30 |
| 3.2 Small incident angle monochromatic plane wave illumination | 36 |
| 3.3 Normal monochromatic TEM ₀₀ mode Gaussian beam illumination | 42 |
| 3.4 Off-axis normal monochromatic TEM ₀₀ mode Gaussian beam illumination | 56 |
| 4. Axial Combination Properties of Dual Microlenses with Normal Monochromatic | |
| Plane Wave Illumination | 62 |
| 4.1 Computational procedure | 63 |
| 4.2 Dual microlenses of the same diameter and profile | 65 |
| 4.2.1 Microlens of 20λ diameter and $1.0 R/D$ ratio | 65 |
| 4.2.2 Microlens of 20λ diameter and $2.5 R/D$ ratio | 78 |
| 4.2.3 Microlens of 5λ and 10λ diameter | 85 |
| 4.3 Dual microlenses of different diameters and profiles | 86 |

| | |
|--|------------|
| 4.3.1 Microlenses of the same diameter but different profiles | 87 |
| 4.3.2 Microlenses of different diameters and profiles | 93 |
| 5. Axial Combination Properties of Dual Microlenses with Normal Monochromatic TEM00 mode Gaussian Beam Illumination | 97 |
| 5.1 Microlens of the same diameter and profile | 99 |
| 5.2 Microlens of the same profile but different diameters | 108 |
| 6. Interference Effect between Dual Parallel-arranged Microlenses with Normal Monochromatic Plane Wave Illumination | 113 |
| 7. Imaging Properties of A Single Microlens | 125 |
| 7.1 Modified Lorentz-Mie theory | 126 |
| 7.2 Imaging of a spherical particle with monochromatic plane wave illumination | 133 |
| 7.2.1 Imaging detectability | 133 |
| 7.2.2 Microlens imaging formula | 145 |
| 7.2.3 Off-axis spherical particle | 148 |
| 7.2.4 Absorptive spherical particle | 150 |
| 7.3 Imaging of a spherical particle with monochromatic TEM00 mode Gaussian beam illumination | 154 |
| 7.3.1 Imaging detectability and imaging formula | 155 |
| 7.3.2 Absorptive spherical particle | 160 |
| 7.3.3 Off-axis spherical particle | 163 |
| 7.3.4 Gaussian beam waist radius | 166 |
| 7.3.5 Off-axis Gaussian beam illumination | 167 |
| 7.3.6 Spherical particle diameter | 168 |
| 7.4 5λ and 10λ diameter microlenses | 170 |

| | |
|---|----------------|
| 8. Summary and Conclusions | 172 |
| 8.1 Summary | 172 |
| 8.2 Future work | 174 |
| References | 176 |
| Appendices | 182 |

PREVIEW

List of Figures

| | |
|---|----|
| Fig. 1.1: Geometry of the thick strip gratings [14] | 7 |
| Fig. 1.2: Geometry of a cylindrical multi-level diffractive lens array [17] | 8 |
| Fig. 1.3: Fresnel lens and its step approximation [18] | 8 |
| Fig. 1.4: The electric field magnitude distributions adjacent to (a) the eight-level diffractive microlens and (b) the binary structure microlens [19] | 10 |
| Fig. 1.5: Two region open boundary continuous profile microlens [31] | 11 |
| Fig. 1.6: Arrangement of the dual open-boundary diffractive microlenses [33] | 12 |
| Fig. 2.1: Prolate spheroidal coordinate system [4] | 15 |
| Fig. 2.2: Oblate spheroidal coordinate system [4] | 16 |
| Fig. 2.3: Microlens profile in the X-Z plane | 17 |
| Fig. 2.4: Microlens profiles of four different R/D ratios. From left to right, the R/D ratio equals 1.0, 1.5, 2.0 and 2.5, respectively | 19 |
| Fig. 3.1: Grey-level plots of the electric field magnitude distribution in the X-Z plane ($Y = 0$) with normal monochromatic plane wave illumination. $D = 5\lambda$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. (a) $R/D = 1.0$. (b) $R/D = 1.5$. (c) $R/D = 2.0$. (d) $R/D = 2.5$. The four plots are displayed using 32 levels between 0.0 and 5.24 | 32 |
| Fig. 3.2: Surface grey-level plot of the electric field magnitude distribution of the focal point in the X-Y plane ($Z = 1.520$). The plot is displayed using 32 levels between 0.0 and 5.24 | 33 |
| Fig. 3.3: CCD imaging sensor with the onchip microlens [48] | 37 |
| Fig. 3.4: Grey-level plot of the electric field magnitude distribution in the X-Z plane ($Y = 0$) with 5° angle of incidence monochromatic plane wave illumination. $D = 5\lambda$, $R/D = 1.0$, $\theta_{inc} = 5^\circ$ and $\theta_{pol} = 0^\circ$. The dashed arrow line indicates the propagation direction of the focused illumination. The plot is displayed using 32 levels between 0.0 and 5.28 | 38 |
| Fig. 3.5: Grey-level plots of the electric field magnitude distributions in the X-Z plane ($Y = 0$) with 10° and 15° angle of incidence monochromatic plane wave illumination. | |

$D = 5\lambda$, $R/D = 1.0$ and $\theta_{pol} = 0^\circ$. (a) $\theta_{inc} = 10^\circ$. (b) $\theta_{inc} = 15^\circ$. The two plots are displayed using 32 levels between 0.0 and 5.2839

Fig. 3.6: Electric field magnitude profiles along the centerline of the focused illumination for four different incident angle monochromatic plane wave illumination40

Fig. 3.7: Grey-level plot of the electric field magnitude distribution of monochromatic TEM00 mode Gaussian beam illumination in the X-Z plane ($Y = 0$). The beam waist is located at the origin and the beam waist radius is 6.6667λ . The electric field polarization direction is set to be along the positive X axis. The plot is displayed using 32 levels between 0.0 and 1.042

Fig. 3.8: Grey-level plot of the electric field magnitude distribution in the X-Z plane with on-axis normal monochromatic TEM00 mode Gaussian beam illumination. $D = 20\lambda$ and $R/D = 1.5$. The incident beam waist radius w_0 equals $1/3$ of the microlens diameter D . The incident beam waist is located at -5.0 on the Z axis. $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. The plot is displayed using 32 levels between 0.0 and 4.0646

Fig. 3.9: Grey-level plot of the electric field magnitude distribution in the X-Z plane ($Y = 0$) for normal monochromatic TEM00 mode Gaussian beam illumination. The beam waist is at 2.96 on the Z axis. The beam waist radius is 1.5546λ . The plot is displayed using 32 levels between 0.0 and 4.0648

Fig. 3.10: Electric field magnitude profiles along the X axis for the transmitted beam and the pure TEM00 mode Gaussian beam illumination. $Y = 0$. (a) $Z = 2.96$. (b) $Z = 5.00$ 48

Fig. 3.11: Plot of the transmitted beam waist position Z' as a function of the incident beam waist position Z . $D = 20\lambda$ and $w_0 = D/3$. The incident and transmitted beam waist positions are normalized by the microlens diameter. The solid line is the exact value obtained using the SVM, the dashed line is the RRM with the microlens actual focal length, and the dotted line is the RRM with the microlens geometrical focal length50

Fig. 3.12: Plots of the transmitted beam waist position Z' as a function of the incident beam waist position Z . $D = 20\lambda$ and $R/D = 1.5$. (a) $w_0 = D/4$. (b) $w_0 = D/6$ 51

Fig. 3.13: Plots of the maximum electric field magnitude of the transmitted beam waist as a function of the incident Gaussian beam waist position. $D = 20\lambda$. (a) $w_0 = D/3$. (b) $w_0 = D/4$. (c) $w_0 = D/6$ 54

Fig. 3.14: Plots of the magnification coefficient as a function of the incident Gaussian beam waist position. $D = 20\lambda$. (a) $w_0 = D/3$. (b) $w_0 = D/4$. (c) $w_0 = D/6$ 55

Fig. 3.15: Grey-level plots of the electric field magnitude distribution of a microlens in the X-Z plane with off-axis normal monochromatic TEM00 mode Gaussian beam illumination. $D = 5\lambda$, $R/D = 1.5$, $w_0 = D/3$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. The incident beam waist is located at (a) $(D/20, -2D)$, (b) $(D/10, -2D)$ and (c) $(3D/20, -2D)$. The three plots are displayed using 32 levels between 0.0 and 1.36558

Fig. 3.16: Electric field magnitude profiles along the X axis for four different off-axis illuminations. $Y = 0$. (a) $Z = 2.12$. (b) $Z = 4.00$. (c) $Z = 6.00$ 60

Fig. 4.1: Grey-level plot of the electric field magnitude distribution in the X-Z plane for the axial combination of dual microlenses. $D = 20\lambda$ and $R/D = 1.0$. The 2nd (right) microlens center $Z_2 = 1.16$ on the Z axis. The plot is displayed using 32 levels between 0.0 and 17.6566

Fig. 4.2: Grey-level plots of the electric field magnitude distribution in the X-Z plane for the axial combination of dual microlenses. $D = 20\lambda$ and $R/D = 1.0$. (a) $Z_2 = 1.76$. (b) $Z_2 = 2.16$. The plots are displayed using 32 levels between 0.0 and 15.7069

Fig. 4.3: Grey-level plots of the electric field magnitude distribution in the X-Z plane for the axial combination of dual microlenses. $D = 20\lambda$ and $R/D = 1.0$. (a) $Z_2 = 2.76$. (b) $Z_2 = 4.16$. The plots are displayed using 32 levels between 0.0 and 15.6570

Fig. 4.4: Grey-level plots of the electric field magnitude distribution in the X-Z plane for the axial combination of dual microlenses. $D = 20\lambda$ and $R/D = 1.0$. (a) $Z_2 = 4.76$. (b) $Z_2 = 5.96$. The plots are displayed using 32 levels between 0.0 and 6.272

Fig. 4.5: Plot of the focus position as a function of the 2nd microlens position. $D = 20\lambda$ and $R/D = 1.0$. The solid and dashed lines represent the focus position calculated using Eq. (4.1) with the microlens actual and geometrical focal lengths, respectively. The square block represents the exact focus position on the shadow side of the 2nd microlens determined using the SVM when the two microlenses are placed closely with each other. The upper-triangular and down-triangular symbols represent the exact primary and secondary focus positions determined using the SVM when the two microlenses are placed relatively far away from each other. The dotted line represents the auxiliary line $Z' = Z$ 73

Fig. 4.6: The time-averaged Poynting Vector distribution in the X-Z plane for the transmitted electromagnetic field through a single microlens at the origin. $D = 20\lambda$ and $R/D = 1.0$ 74

Fig. 4.7: Grey-level plot of the electric field magnitude distribution in the X-Z plane for the axial combination of dual microlenses. $D = 20\lambda$ and $R/D = 1.0$. $Z_2 = 9.16$. $E_{max} = 3.92$. The plot is displayed using 32 levels between 0.0 and 3.9276

Fig. 4.8: Plot of the magnification coefficient of the 2nd microlens as a function of the 2nd microlens position. $D = 20\lambda$ and $R/D = 1.0$. The solid and dash lines represent the magnification coefficients calculated using Eq. (4.1) with the microlens actual and geometrical focal lengths, respectively. The square block symbol represents the exact magnification coefficient on the shadow side of the 2nd microlens determined using the SVM when the two microlenses are placed closely with each other. The upper-triangular and down-triangular symbols represent the exact primary and secondary magnification coefficients determined using the SVM when the two microlenses are placed relatively far away from each other77

Fig. 4.9: Grey-level plots of the electric field magnitude distribution in the X-Z plane for the axial combination of dual microlenses. $D = 20\lambda$ and $R/D = 2.5$. (a) $Z_2 = 0.40$. (b) $Z_2 = 0.80$. (c) $Z_2 = 1.20$. The plots are displayed using 32 levels between 0.0 and 10.7580

Fig. 4.10: Grey-level plots of the electric field magnitude distribution in the X-Z plane for the axial combination of dual microlenses. $D = 20\lambda$ and $R/D = 2.5$. (a) $Z_2 = 4.40$. (b) $Z_2 = 7.20$. (c) $Z_2 = 8.80$. (d) $Z_2 = 11.60$. The plots are displayed using 32 levels between 0.0 and 8.6481

Fig. 4.11: The time-averaged Poynting Vector distribution in the X-Z plane for the transmitted electromagnetic field through a single microlens at the origin. $D = 20\lambda$ and $R/D = 2.5$ 83

Fig. 4.12: Plot of the focus position as a function of the 2nd microlens position. $D = 20\lambda$ and $R/D = 2.5$ 84

Fig. 4.13: Plot of the magnification coefficient of the 2nd microlens as a function of the 2nd microlens position. $D = 20\lambda$ and $R/D = 2.5$ 84

Fig. 4.14: Grey-level plots of the electric field magnitude distribution in the X-Z plane for the axial combination of dual microlenses. For both microlenses, $D = 20\lambda$. $R/D = 1.0$ for the 1st microlens and $R/D = 2.5$ for the 2nd microlens. (a) $Z_2 = 0.80$. (b) $Z_2 = 1.20$. (c) $Z_2 = 1.60$. The plots are displayed using 32 levels between 0.0 and 15.1089

Fig. 4.15: Grey-level plots of the electric field magnitude distribution in the X-Z plane for the axial combination of dual microlenses. For both microlenses, $D = 20\lambda$. $R/D = 2.5$ for the 1st microlens and 1.0 for the 2nd microlens. (a) $Z_2 = 0.7071$. (b) $Z_2 = 1.0606$. (c) $Z_2 = 1.4141$. The plots are displayed using 32 levels between 0.0 and 15.5090

Fig. 4.16: Grey-level plots of the electric field magnitude distribution in the X-Z plane for the axial combination of dual microlenses. $D = 20\lambda$. (a) $R/D = 1.0$ for the 1st

microlens and $R/D = 2.5$ for the 2nd microlens. $Z_2 = 5.20$. (b) $R/D = 2.5$ for the 1st microlens and $R/D = 1.0$ for the 2nd microlens. $Z_2 = 6.0096$. The plots are displayed using 32 levels between 0.0 and 9.6092

Fig. 4.17: Grey-level plots of the electric field magnitude distribution in the X-Z plane for the axial combination of dual microlenses. $D = 20\lambda$ and $R/D = 1.0$ for the 1st microlens. (a) $D = 10\lambda$ and $R/D = 1.0$ for the 2nd microlens. $Z_2 = 1.60$. (b) $D = 10\lambda$ and $R/D = 2.5$ for the 2nd microlens. $Z_2 = 1.20$. The plot is displayed using 32 levels between 0.0 and 20.1094

Fig. 4.18: Grey-level plots of the electric field magnitude distribution in the X-Z plane for the axial combination of dual microlenses. $D = 20\lambda$ and $R/D = 1.0$ for the 1st microlens. (a) $D = 5\lambda$ and $R/D = 1.0$ for the 2nd microlens. $Z_2 = 1.60$. (b) $D = 5\lambda$ and $R/D = 2.5$ for the 2nd microlens. $Z_2 = 1.60$. The plots are displayed using 32 levels between 0.0 and 18.9096

Fig. 5.1: Grey-level plot of the electric field magnitude distribution in the X-Z plane with normal monochromatic TEM00 mode Gaussian beam illumination. $D = 20\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. The Z coordinate of the 2nd microlens $Z_2 = 1.16$. The incident beam waist radius $w_0 = D/3$ and the incident beam waist is positioned at $-D$ on the Z axis. The transmitted beam waist radius $w'_0 = 0.09105$. The plot is displayed using 32 levels between 0.0 and 8.3299

Fig. 5.2: Grey-level plots of the electric field magnitude distribution in the X-Z plane with normal monochromatic TEM00 mode Gaussian beam illumination. $D = 20\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. (a) $Z_2 = 1.56$. $E_{max} = 7.4428$. $w'_0 = 0.0978$. (b) $Z_2 = 3.16$. The plots are displayed using 32 levels between 0.0 and 7.50101

Fig. 5.3: Grey-level plot of the electric field magnitude distribution in the X-Z plane with normal monochromatic TEM00 mode Gaussian beam illumination. $D = 20\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. $Z_2 = 5.96$. $E_{max} = 2.4152$. $w'_0 = 0.23515$. The plot is displayed using 32 levels between 0.0 and 3.43102

Fig. 5.4: Plot of the transmitted beam waist position as a function of the 2nd microlens position. The solid and dashed lines are the transmitted beam waist positions calculated using the RRM with the microlens actual and geometrical focal lengths, respectively. The solid block is the exact value determined using the SVM in the oblate spheroidal coordinate system103

Fig. 5.5: Plot of the magnification coefficient as a function of the 2nd microlens position. The solid and dashed lines are the magnification coefficients calculated using the RRM with the microlens actual and geometrical focal lengths, respectively. The

solid blocks are the exact value calculated using the SVM in the oblate spheroidal coordinate system104

Fig. 5.6: Plots of the transmitted beam waist position as a function of the 2nd microlens position. $D = 20\lambda$ and $R/D = 1.0$. (a) $w_0 = D/4$. (b) $w_0 = D/6$. The incident beam waist is located at $-D$ on the Z axis105

Fig. 5.7: Plots of the magnification coefficient as a function of the 2nd microlens position. $D = 20\lambda$ and $R/D = 1.0$. (a) $w_0 = D/4$. (b) $w_0 = D/6$. The incident beam waist is located at $-D$ on the Z axis106

Fig. 5.8: Grey-level plot of the electric field magnitude distribution in the X-Z plane with normal monochromatic TEM00 mode Gaussian beam illumination. For the 1st microlens $D = 20\lambda$ and for the 2nd microlens $D = 10\lambda$. $R/D = 1.0$, $Z_2 = 1.16$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. $w_0 = D/3$ and the incident beam waist is placed at $-D$ on the Z axis. The plot is displayed using 32 levels between 0.0 and 9.35110

Fig. 5.9: Grey-level plot of the electric field magnitude distribution in the X-Z plane with normal monochromatic TEM00 mode Gaussian beam illumination. For the 1st microlens $D = 20\lambda$ and for the 2nd microlens $D = 5\lambda$. $R/D = 1.0$, $Z_2 = 1.96$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. $w_0 = D/3$ and the incident beam waist is placed at $-D$ on the Z axis. The plot is displayed using 32 levels between 0.0 and 9.90110

Fig. 5.10: Grey-level plot of the electric field magnitude distribution in the X-Z plane with normal monochromatic TEM00 mode Gaussian beam illumination. For the 1st microlens $D = 10\lambda$ and for the 2nd microlens $D = 5\lambda$. $R/D = 1.0$, $Z_2 = 1.16$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. $w_0 = D/3$ and the incident beam waist is placed at $-D$ on the Z axis. The plot is displayed using 32 levels between 0.0 and 5.14111

Fig. 6.1: Grey-level plots of the electric field magnitude distribution in the X-Z plane with 0° angle of incidence monochromatic plane wave illumination. $D = 5\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. (a) The spacing between the dual microlens $L = D$. (b) $L = 3D/4$. (c) $L = D/2$. (d) $L = D/4$. (e) $L = D/8$. The plots are displayed using 32 levels between 0.0 and 5.26117

Fig. 6.2: Grey-level plot of the electric field magnitude distribution in the X-Z plane with 0° angle of incidence monochromatic plane wave illumination. $D = 5\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. $L = D/8$. $E_{max} = 5.2570$. $d = 0.6208$. The plot is displayed using 32 levels between 0.0 and 5.26120

Fig. 6.3: Grey-level plots of the electric field magnitude distribution in the X-Z plane with 0° angle of incidence monochromatic plane wave illumination. $D = 10\lambda$,

$R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. (a) $L = D$. (b) $L = 3D/4$. (c) $L = D/2$. (d) $L = D/4$. (e) $L = D/8$. The plots are displayed using 32 levels between 0.0 and 7.26123

Fig. 6.4: Grey-level plot of the electric field magnitude distribution in the X-Z plane with 0° angle of incidence monochromatic plane wave illumination. $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. $L = D/8$. $E_{max} = 7.2466$. $d = 0.3622$. The plot is displayed using 32 levels between 0.0 and 7.26124

Fig. 7.1: Grey-level plots of the electric field magnitude distribution in the X-Z plane ($Y = 0$) with 0° angle of incidence monochromatic plane wave illumination. $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. (a) $D_{sphere} = 2\lambda$, $X_{sphere} = 0.0$ and $Z_{sphere} = -4.0$. (b) Without a spherical particle. The plots are displayed using 32 levels between 0.0 and 8.00134

Fig. 7.2: Grey-level plot of the electric field magnitude distribution in the X-Z plane ($Y = 0$) with 0° angle of incidence monochromatic plane wave illumination (without the plane wave field background). $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. $D_{sphere} = 2\lambda$, $X_{sphere} = 0.0$ and $Z_{sphere} = -4.0$. The plot is displayed using 32 levels between -1.18 and 3.00137

Fig. 7.3: Grey-level plots of the electric field magnitude distribution in the X-Z plane ($Y = 0$) with 0° angle of incidence monochromatic plane wave illumination. $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. $X_{sphere} = 0.0$ and $Z_{sphere} = -4.0$. (a) $D_{sphere} = 1\lambda$. With the plane wave background field pattern. The plot is displayed using 32 levels between 0.0 and 8.0. (b) $D_{sphere} = 1\lambda$. Without the plane wave background field pattern. The plot is displayed using 32 levels between -0.265 and 1.190. (c) $D_{sphere} = 1.5\lambda$. With the plane wave background field pattern. The plot is displayed using 32 levels between 0.0 and 8.0. (d) $D_{sphere} = 1.5\lambda$. Without the plane wave background field pattern. The plot is displayed using 32 levels between -0.790 and 2.160139

Fig. 7.4: Grey-level plots of the electric field magnitude distribution in the X-Y plane ($Z = 3.1773$) with 0° angle of incidence monochromatic plane wave illumination. $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. (a, b, c) $X_{sphere} = 0.0$ and $Z_{sphere} = -4.0$. With the plane wave background field pattern. (a) $D_{sphere} = 1\lambda$. (b) $D_{sphere} = 1.5\lambda$. (c) $D_{sphere} = 2\lambda$. (d) The plane wave field background. The plots are displayed using 32 levels between 0.0 and 4.0141

Fig. 7.5: Grey-level plots of the electric field magnitude distribution in the X-Y plane ($Z = 3.1773$) with 0° angle of incidence monochromatic plane wave illumination

(without the plane wave background field pattern). $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. $X_{sphere} = 0.0$ and $Z_{sphere} = -4.0$. (a) $D_{sphere} = 1\lambda$. (b) $D_{sphere} = 1.5\lambda$. (c) $D_{sphere} = 2\lambda$. The plot is displayed using 32 levels between -2.0 and 1.0142

Fig. 7.6: Electric field magnitude profiles along the Y axis of the image plane ($X = 0$, $Z = 3.1773$) with 0° angle of incidence monochromatic plane wave illumination (without the plane wave field background). $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$ 143

Fig. 7.7: Grey-level plots of the electric field magnitude distribution in the X-Z plane ($Y = 0$) with 0° angle of incidence monochromatic plane wave illumination. $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. $D_{sphere} = 2\lambda$. $X_{sphere} = 0.0$. (a, b) $Z_{sphere} = -6.0$. (a) With the plane wave field background. The plot is displayed using 32 levels between 0.0 and 8.0. (b) Without the plane wave field background. The plot is displayed using 32 levels between -1.16 and 2.94. (c, d) $Z_{sphere} = -8.0$. (c) With the plane wave field background. The plot is displayed using 32 levels between 0.0 and 8.0. (d) Without the plane wave field background. The plot is displayed using 32 levels between -0.820 and 0.275146

Fig. 7.8: Electric field magnitude profiles along the Y axis of the image plane with 0° angle of incidence monochromatic plane wave illumination (without the plane wave field background). $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. $D_{sphere} = 2\lambda$ 148

Fig. 7.9: Grey-level plots of the electric field magnitude distribution in the X-Z plane ($Y = 0$) with 0° angle of incidence monochromatic plane wave illumination (with the plane wave field background). $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. $D_{sphere} = 2\lambda$. $X_{sphere} = 0.0$ and $Z_{sphere} = -4.0$. (a) $\tilde{n} = (1.33, 0.1j)$. (b) $\tilde{n} = (1.33, 0.5j)$. The plots are displayed using 32 levels between 0.0 and 8.0152

Fig. 7.10: Electric field magnitude profiles along the Z axis with 0° angle of incidence monochromatic plane wave illumination153

Fig. 7.11: Grey-level plots of the electric field magnitude distribution in the X-Y plane ($Z = 3.1773$) with 0° angle of incidence monochromatic plane wave illumination (without the plane wave field background). $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 0^\circ$ and $\theta_{pol} = 0^\circ$. $D_{sphere} = 2\lambda$. $X_{sphere} = 0.0$ and $Z_{sphere} = -4.0$. (a) $\tilde{n} = (1.33, 0.1j)$. (b) $\tilde{n} = (1.33, 0.5j)$. The plots are displayed using 64 levels between -2.0 and 1.0154

Fig. 7.12: Grey-level plots of the electric field magnitude distribution in the X-Z plane ($Y = 0$) with 90° angle of incidence monochromatic TEM00 mode Gaussian beam

illumination. $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 90^\circ$ and $\theta_{pol} = 0^\circ$. $D_{sphere} = 2\lambda$. $X_{sphere} = 0.0$ and $Z_{sphere} = -4.0$. (a) The plot is displayed using 64 levels between 0.0 and 4.0. (b) The plot is displayed using 32 levels between 0.0 and 0.08156

Fig. 7.13: Grey-level plot of the electric field magnitude distribution in the image plane ($Z = 3.1773$) with 90° angle of incidence monochromatic TEM00 mode Gaussian beam illumination. $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 90^\circ$ and $\theta_{pol} = 0^\circ$. $D_{sphere} = 2\lambda$. $X_{sphere} = 0.0$ and $Z_{sphere} = -4.0$. The plot is displayed using 32 levels between 0.0 and 0.08158

Fig. 7.14: Grey-level plots of the electric field magnitude distribution with 90° angle of incidence monochromatic TEM00 mode Gaussian beam illumination. $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 90^\circ$ and $\theta_{pol} = 0^\circ$. $D_{sphere} = 2\lambda$. $X_{sphere} = 0.0$. (a) $Z_{sphere} = -5.0$. Electric field magnitude distribution in the X-Z plane ($Y = 0$). (b) $Z_{sphere} = -5.0$. Electric field magnitude distribution in the image plane ($Z = 2.6136$). (c) $Z_{sphere} = -6.0$. Electric field magnitude distribution in the X-Z plane ($Y = 0$). (d) $Z_{sphere} = -6.0$. Electric field magnitude distribution in the image plane ($Z = 2.3939$). The plots are displayed using 32 levels between 0.0 and 0.08159

Fig. 7.15: Grey-level plots of the electric field magnitude distribution with 90° angle of incidence monochromatic TEM00 mode Gaussian beam illumination. $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 90^\circ$ and $\theta_{pol} = 0^\circ$. $D_{sphere} = 2\lambda$. $X_{sphere} = 0.0$ and $Z_{sphere} = -4.0$. (a) $\tilde{n} = (1.33, 0.1j)$. Electric field magnitude distribution in the X-Z plane ($Y = 0$). (b) $\tilde{n} = (1.33, 0.1j)$. Electric field magnitude distribution in the image plane ($Z = 3.1773$). (c) $\tilde{n} = (1.33, 0.5j)$. Electric field magnitude distribution in the X-Z plane ($Y = 0$). (d) $\tilde{n} = (1.33, 0.5j)$. Electric field magnitude distribution in the image plane ($Z = 3.1773$). The plot is displayed using 32 levels between 0.0 and 0.08161

Fig. 7.16: Grey-level plots of the electric field magnitude distribution in the image plane ($Z = 3.1773$) with 90° angle of incidence monochromatic TEM00 mode Gaussian beam illumination. $D = 10\lambda$, $R/D = 1.0$, $\theta_{inc} = 90^\circ$ and $\theta_{pol} = 0^\circ$. $Z_{sphere} = -4.0$. (a) $X_{sphere} = D/16$. (b) $X_{sphere} = D/8$. (c) $X_{sphere} = 3D/16$. (d) $X_{sphere} = D/4$. The plots are displayed using 32 levels between 0.0 and 0.08164

Fig. 7.17: Electric field magnitude profiles along the X axis of the image plane. The incident beam waist radius increases along the arrow direction167

Fig. 7.18: Electric field magnitude profiles along the X axis of the image plane168

Fig. 7.19: Electric field magnitude profiles along the X axis of the image plane170

List of Tables

| | |
|--|-----|
| Tables 3.1: Nondimensionlized semi-major and semi-minor axis lengths of the four different profile microlenses | 34 |
| Table 3.2: Focusing characteristics of the 5λ diameter microlens | 35 |
| Table 3.3: Focusing characteristics of the 10λ diameter microlens | 35 |
| Table 3.4: Focusing characteristics of the 20λ diameter microlens | 36 |
| Table 3.5: Focusing characteristics of the 5λ diameter microlens with small incident angle plane wave illumination | 39 |
| Table 3.6: Focusing characteristics of the 10λ diameter microlens with small incident angle plane wave illumination | 41 |
| Table 3.7: Focusing characteristics of the 20λ diameter microlens with small incident angle plane wave illumination | 41 |
| Table 3.8: Characteristics of the transmitted beam waist for off-axis monochromatic TEM00 mode Gaussian beam illumination. $D = 5\lambda$ and $R/D = 1.5$ | 59 |
| Table 6.1: The focusing characteristics for the five different spacing arrangements. $D = 5\lambda$ and $R/D = 1.0$. Z' is the Z coordinate of the center of the focused beam ... | 117 |
| Table 6.2: The focus characteristics of the five different arrangements. $D = 10\lambda$ and $R/D = 1.0$. Z' is the Z coordinate of the center of the focused beam | 123 |

Nomenclature

∇ del operator

∇^2 Laplace operator

β spheroidal radial function type = 1, 2, 3

λ electromagnetic field wavelength

$\lambda_{l,m}$ eigenvalue that corresponds to the scalar eigenfunction $\Pi_{l,m}$

ε electric permittivity

ε_{ext} dielectric constant of the external medium

ε_r dielectric constant

$\tilde{\varepsilon}$ complex dielectric constant = $\varepsilon_r + j4\pi\sigma / \omega$

ϕ spheroidal azimuthal angle coordinate

$\hat{\phi}$ spheroidal azimuthal angle vector

η spheroidal angle coordinate

η_0 spheroidal angle

$\hat{\eta}$ spheroidal angle vector

μ magnetic permeability

π Pi

θ angle between the vector parallel to the microlens surface and that parallel to the spheroidal surface

θ_{inc} incident angle of the incident electromagnetic illumination

θ_{pol} electric field polarization angle of the incident electromagnetic illumination

σ electric conductivity

ω angular speed of the incident electromagnetic field

ξ spheroidal radial coordinate

ξ_0 spheroidal radius

$\hat{\xi}$ spheroidal radius vector

$\xi_l^{(1)} = \psi_l - j\chi_l$

- Π scalar eigenfunction solution of the scalar Helmholtz equation
- $\hat{\Pi}$ vector eigenfunction solution of the vector Helmholtz equation
- $\psi_l(kr)$, $\chi_l(kr)$ Ricatti-Bessel functions
- \mathbf{A} arbitrary vector on the microlens' surface
- $A_{l,m}$ expansion coefficient
- $A_{l,m}^s$, $A_{l,m}^\phi$ integrals that depend on both the microlens geometry and the incident illumination setting
- a semi-major axis length of the pure oblate spheroid and the microlens
- $a_{l,m}$ expansion coefficient
- $B_{l,m}$ expansion coefficient
- $B_{l,m}^s$, $B_{l,m}^\phi$ integrals that depend on both the microlens geometry and the incident illumination setting
- b semi-minor axis length of the pure oblate spheroid
- b' semi-minor axis length of the microlens
- $b_{l,m}$ expansion coefficient
- C_0 , C_2 , C_4 coefficients
- $c_{l,m}$ expansion coefficient
- d distance between dual microlenses, focus diameter
- $d_{l,m}$ expansion coefficient
- D microlens diameter
- D_{sphere} sphere diameter
- e Euler's number
- \mathbf{E} electric field vector
- E_0 the maximum electric field magnitude of the incident illumination
- E_{max} the maximum electric field magnitude of the focus region
- $e_{l,m}$ expansion coefficient
- f microlens focal length
- f_b microlens back focal length

f_e microlens effective focal length

f_{act} microlens actual focal length

f_{geo} microlens geometrical focal length

f_{semi} semi-focal length of the oblate spheroidal coordinate system

\mathbf{H} magnetic field vector

h spheroidal coordinate size parameter $= kf_{semi}$

h_b distance between the microlens back principal plane and the microlens back spherical surface vertex

h_{ext} spheroidal coordinate size parameter for the external electromagnetic field $= k_{ext}f_{semi}$

h_f distance between the microlens front principal plane and the microlens front spherical surface vertex

h_{int} spheroidal coordinate size parameter for the internal electromagnetic field $= k_{int}f_{semi}$

$I_{l,m,l'}^{1-8}$ integral that depends only on the microlens geometry

j imaginary unit, $j^2 = -1$

\mathbf{k}_0 propagation vector of the incident electromagnetic illumination

k wave number of the electromagnetic field

k_0 wave number of the electromagnetic field in the vacuum

$k_1 = jk_0\tilde{\mathcal{E}}$

$k_2 = jk_0$

L upper limit of l index, distance between dual parallel-arranged microlenses

l integer index

l' integer index

$\mathbf{M}_{l,m}$ independent vector eigenfunction solution of the vector Helmholtz equation

M upper limit of m index, magnification coefficient

m integer index

$\mathbf{N}_{l,m}$ independent vector eigenfunction solution of the vector Helmholtz equation

n relative refractive index of the microlens

\tilde{n} complex relative refractive index

- \hat{n} unit vector perpendicular to the microlens' surface
- \mathbf{P} time-averaged Poynting Vector
- R radius of curvature of the microlens spherical surface
- $R_{l,m}^{(\beta)}(h, \xi)$ spheroidal radial function
- RRM Rayleigh range method
- \mathbf{r} position vector
- SVM Separation-of-Variables method
- $S_{l,m}(h, \eta)$ spheroidal angle function
- s object distance
- s_e effective object distance
- s' image distance
- s'_e effective image distance
- \hat{s} unit vector parallel to the microlens' surface and perpendicular to $\hat{\phi}$
- t time
- w_0 incident beam waist radius
- w'_0 transmitted beam waist radius
- X_{sphere} X coordinate of the spherical particle center
- $Y_{l,m}(\theta, \phi)$ spherical harmonic function
- Z Z coordinate of the incident beam waist
- Z' Z coordinate of the transmitted beam waist or the focused beam
- Z_2 Z coordinate of the 2nd microlens
- Z_R Rayleigh range of the incident TEM00 mode Gaussian beam illumination
- Z_{sphere} Z coordinate of the spherical particle center

Chapter 1. Introduction

Optical elements are widely used in the laboratory experiments and commercial applications. The regular-size optical element is most commonly used and its optical properties can be accurately described using classic geometrical optics theory [1]. Due to the relatively large size and weight, regular-size optical elements are prohibited from high capacity and minimized optical equipment applications. With the development of micro- and nano- fabrication technology [2] in the past few decades, a new type of optical element is fabricated in the micro scale, which is called the “micro optical element”, with its characteristic size on the order of the optical wavelength. This new type of micro optical element has raised great research interests for its novel optical properties and minimized size and weight.

As the characteristic size of the micro optical element is comparable with the optical wavelength, based on the Huygens-Fresnel diffraction theory, the Fresnel diffraction effect [3] through the micro optical element aperture becomes relatively strong in comparison with that through the regular-size optical element and leads to optical properties quite different from that given by geometrical optics theory. Fundamentally, the investigation of the optical properties of micro optical element is equivalent to the study of the interaction of micro optical element with electromagnetic waves. The computational electromagnetics method can be applied to investigate this interaction by calculating the electromagnetic field distributions inside of and adjacent to the micro optical element. The corresponding optical properties of the micro optical element can then be deduced from the calculated electromagnetic field distributions. The

optical properties of different type and profile micro optical elements have been previously investigated using diverse analytical and computational methods. While the systematic research work on the optical properties of micro optical systems has not been conducted before. In this dissertation, the three-dimensional continuous profile symmetrical biconvex microlens is considered. The frequency domain full-field analytical oblate spheroidal coordinate system Separation-of-Variables method (SVM) [4] is applied to study the optical properties of microlens optical systems with monochromatic plane wave and TEM00 mode Gaussian beam illumination.

In Chapter 1, an overview of the analytical and numerical computational electromagnetics methods and a review of the research progress on the optical properties of the micro optical element are presented. In Chapter 2, the oblate spheroidal coordinate system and the geometry of the three-dimensional continuous profile symmetrical biconvex microlens are described first. Then brief introduction to the Separation-of-Variables method (SVM) in the oblate spheroidal coordinate system follows. The two types of illumination sources used in this work, monochromatic plane wave and TEM00 mode Gaussian beam, are also introduced. In Chapter 3, the focusing properties of a single microlens with arbitrary monochromatic plane wave illumination are studied. The beam transformation properties of a single microlens with monochromatic TEM00 mode Gaussian beam illumination are also discussed. In Chapter 4, the axial combination properties of dual microlenses with monochromatic plane wave illumination are investigated. In Chapter 5, the beam transformation properties through dual microlenses with monochromatic TEM00 mode Gaussian beam illumination are studied. In Chapter 6, the interference properties between dual parallel-arranged microlenses with